



Docket No. 740756-2045

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

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Inventor's name(s): Kenji ITOH et al.

) Group Art Unit: 1762

Serial No. 09/412,510

) Examiner: M. Padgett

Filed: October 5, 1999

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For: PROCESS FOR TREATING A
SUBSTRATE WITH A PLASMA

) Date: September 12, 2001

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Keda
9/21/01
NC

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on September 12, 2001.

[mailer's name]

AMENDMENT

Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Final Office Action dated May 11, 2001 and further to the attached Request for Continued Examination (RCE), please amend the above identified application as follows.

IN THE SPECIFICATION:

Please delete the first sentence of the specification and insert --This application is a divisional of U.S. Application Serial No. 08/604,713, now U.S. Patent No. 6,001,431, filed February 21, 1996, which itself is a continuation of U.S. Appln. Serial No. 08/173,961, filed December 28, 1993, now abandoned.--

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IN THE CLAIMS:

Please cancel claims 1, 18, and 19 without prejudice or disclaimer.

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RCE
SEP 17 2001
TC 1700